

**AMENDMENTS TO THE SPECIFICATION:**

Replace the paragraph beginning at line 16, page 20, with the following rewritten paragraph:

When the operation microscope 25 which is at the retreat position as described above is ~~wanted to return~~ is to be returned to the observation position near the surgical region, the operator operates the downward-rough-motion switch 31 to input the operation signal from the downward-rough-motion switch 31 to the arithmetic and control circuit 27.

Replace the paragraph beginning at line 20, page 33, with the following rewritten paragraph:

In this state, when the fixing screws [[1a]] 7a and 15 are loosened to move the operation microscope 25 from right to left or up and down while holding it, the second arm 6 is horizontally rotated about the rotation shaft (not shown) of the first support member 7 and swung upward and downward. Therefore, the operation microscope 25 can be moved to a target location. In addition, when the fixing screw 21 is loosened, the operation microscope 25 can be rotated together with the support shaft 20b about its axis. Therefore, an orientation of the operation microscope 25 in the horizontal direction can be changed by the rotational operation.

Replace the paragraph beginning at line 27, page 45, with the following rewritten paragraph:

Also, the operation microscope apparatus according to the embodiment of the present invention includes: the operation microscope 25 supported to the pillar [[2]] 3 through the electrically-operated elevating device for rough-motion (first electrically-operated upward-and-

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downward-motion device 17); the lens support arm 51 supported to the support portion of the operation microscope so as to be movable between the use position at which the lens support arm is extended downward and the storage position at which the lens support arm is stored upward; the front lens 74 held by the lens supported arm; a control unit (arithmetic and control circuit 27) for controlling the electrically-operated elevating device; and switches (30 and 31; 94 and 95) for upward-and-downward-rough-motion. A detection unit (microswitch 91) for detecting the storage state of the lens support arm 51 to output a detection signal is provided in the operation microscope apparatus. Only when the detection signal of the storage state is received, the control unit (arithmetic and control circuit 27) controls the electrically-operated elevating device (first electrically-operated upward-and-downward-motion device 17) in accordance with the operation of the switches (30 and 31; 94 and 95) to allow the operation microscope 25 to roughly move upward and downward.